

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
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SERIAL NO. 09/719825

INFORMATION DISCLOSURE
STATEMENT BY APPLICANT

(Use several sheets if necessary)

(37 CFR 1.98(b))

APPLICANT
Bernard DREVILLIONFILING DATE
December 18, 2000

GROUP

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		PATENT NUMBER	ISSUE DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
WD	AA	5,277,747	01-94	ASPNES			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						

FOREIGN PATENT OR PUBLISHED FOREIGN PATENT APPLICATION

		DOCUMENT NO.	PUBL. DATE	COUNTRY OR PATENT OFFICE	CLASS	SUB CLASS	TRANSLATION YES NO
WD	AJ	2 731 074.	08-96	FRANCE			NO
	AK						
	AL						
	AM						
	AN						

OTHER DOCUMENTS (Including Author, Title, Date, Relevant Pages, Place of Publication)

AO	Shiuh CHAO et al., " <u>POLARIZED LIGHT SCATTERING BY SILICON OXIDE THIN FILM EDGE ON SILICON: AN EXPERIMENTAL APPROACH FOR THIN FILM THICKNESS DETERMINATION</u> ", Measurement Science and Technology, July 3, 1990
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EXAMINER

Wille Davis

DATE CONSIDERED

12-5-02

EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered.
Include copy of this form with next communication to applicant.